



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: SHINCHIRO YAGI Confirmation No.: 8468
Serial No.: 09/914,044 Atty Docket No.: 155/50324
Filed: December 11, 2001 Group Art Unit: 2851
Customer No.: 23911 Examiner: Fuller, Rodney Evan
Title: INSPECTION OBJECT SILICON WAFER FOR THE PURPOSE
OF DETECTING CRYSTAL DEFECTS AND THE METHOD OF
DETECTING THEREOF

**LETTER TO THE OFFICIAL DRAFTSMAN SUBMITTING FORMAL
DRAWINGS**

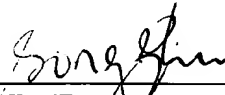
Mail Stop ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

2 sheets of Formal drawings (showing Figs. 3a, 3b, and 4) meeting the
requirements of 37 CFR § 1.84 are hereby submitted.

Respectfully submitted,

May 6, 2004

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